This Sheet Has Been Replaced



ABSTRACT OF THE DISCLOSURE

An Al electrode film is formed on a surface wave element substrate within a belljar, and coated with a nitride film (aluminum nitride film) or oxide film (aluminum oxide film) serving as an insulating film with a N_2 gas or O_2 gas being introduced into the belljar after the formation of the Al electrode film. The insulating film can eliminate the adverse influences of metallic particles caused by the peeling-off of the plating on the back surface of a metallic cap and the welding of the metallic cap to a base, thus reducing the insulating resistance loss as well as preventing corrosion of the electrodes during a dicing process.